

Docket No. AM 1562D1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Divisional Application of

JOAN WANG

Parent Serial No.: 08/867,229

Parent Filed: June 2, 1997

For: METHOD OF ETCHING HIGH ASPECT
RATIO OPENINGS IN SILICON

PETITION UNDER 37 CFR 1.84(b)(1)

To: Assistant Commissioner for Patents
Washington, DC 20231

Sir:

Applicants petition that the Assistant Commissioner accept
THREE sheets of photomicrographs bearing Figures 3, 4, 5, 6, 7
and 8 thereon. Three copies of each sheet are attached.

Please charge the Petition fee of \$130.00 to Deposit Account
13-4542. A duplicate of this Petition is attached.

Respectfully submitted,

JOAN WANG

By


Birgit E. Morris

Registration No. 24,484

06/15/01
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06/15/01

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Please continue to send all correspondence to

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I hereby certify that this correspondence is
being deposited with the United States Postal
Service as first class mail in an envelope
addressed to The Assistant Commissioner for
Patents, Washington, DC 20231, on

June 15, 2001
Date of Deposit

William E. Morris
Name of person making deposit

Signature